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(54) Title: FLUID DELIVERY MODULE

(57) Abstract: Apparatuses for controlling fluid flow are important components for delivering process fluids for semiconductor fabrication. These apparatuses for controlling fluid flow are formed with a variety of fluid flow components, including fluid flow components for measuring various properties of process fluids. Fluid flow components for measuring may be constructed to monitor properties such as temperature and pressure, and may do so via sensing elements which also serve to enclose a portion of a flow path within the fluid flow component.

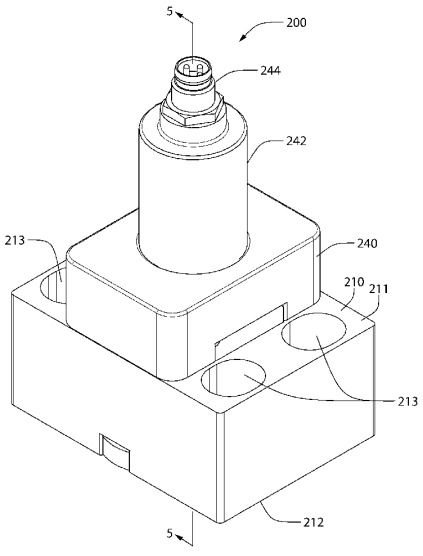


FIG. 3

WO 2023/163819 A1